DEPOSITION SYSTEMS, ALD SYSTEMS, CVD SYSTEMS, DEPOSITION METHODS, ALD METHODS AND CVD METHODS

ABSTRACT

Some embodiments include deposition systems configured for reclaiming unreacted precursor with one or more traps provided downstream of a reaction chamber. Some of the deposition systems may utilize two or more traps that are connected in parallel relative to one another and configured so that the traps may be alternately utilized for trapping precursor and releasing trapped precursor back into the reaction chamber. Some of the deposition systems may be configured for ALD, and some may be configured for CVD.

FIGURE 1